

IFW

00862.023171

PATENT APPLICATION



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

TAKASHI ARAI

Application No.: 10/634,860

Filed: August 6, 2003

For: METHOD OF STORING
MATERIAL INTO WHICH GAS
SATURATES

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: Examiner: Not Yet Assigned
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: Group Art Unit: 1731
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)
: February 2, 2006

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

FOURTH INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents are enclosed.

This Information Disclosure Document is to submit complete English language translations of JP 2003-073496 and JP 2003-327826, which were cited in the Third Information Disclosure Statement filed on December 1, 2005.

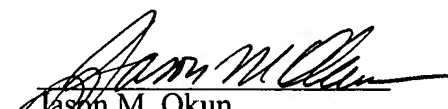
CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

It is believed that no fee is due in connection with this Information Disclosure Statement. However, if such a fee is deemed necessary, the Commissioner is authorized to charge it to Deposit Account 06-1205. Any overpayment should be credited to the same Deposit Account.

Applicant's undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,


Jason M. Okun
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Registration No. 48,512

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